End-Effector Accessory

End-Effector Change Station - mECS

The end-effector change station is designed to provide a fully automated changing of the end-effector during the work process.

Features

• different end-effector sizes (6”/8”)
• storing of up to six end-effectors

End-Effector Cleaner - mEC

The end-effector cleaner is designed for fully automated cleaning of end-effectors in the course of exchange at the end-effector change station.

Features

• different end-effector sizes (6”/8”)
• cleaning with CDA or N₂
• optional with transfer station for throughput optimization

Transfer Station - mTS

The transfer station is designed to store a wafer temporarily while e.g. the robot takes a different end-effector for further process.

Features

• different wafer sizes (6”/8”)
• storing of a wafer (e.g. change back side to front side handling)
• optional with OCR reader and/or end-effector cleaner